

Notice of References Cited			Application/Control No.	Applicant(s)/Patent Under Reexamination FELTON ET AL.
			Examiner Roberts Culbert	Art Unit 1763

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-5,824,177	10-1998	Yoshihara et al.	156/250
*	B	US-6,555,417	04-2003	Spooner et al.	438/113
*	C	US-2002/0088988	07-2002	Silverbrook, Kia	257/99
*	D	US-2002/0090180	07-2002	Silverbrook, Kia	385/92
*	E	US-2003/0092229	05-2003	Silverbrook, Kia	438/200
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	I	US-			
	J	US-			
	K	US-			
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FOREIGN PATENT DOCUMENTS

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	O	JP 2001269900 A	10-2001	Japan	PINTER et al.	B81C 01/00
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages
	U	Yoshio Awatani et al., "Damage Free Dicing Method for MEMS Devices" International Conference on Optical MEMS; Conference Digest pp. 137-138, August 20-23, 2002.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.